



BOX AF
RESPONSE UNDER 37 C.F.R. § 1.116
EXPEDITED PROCEDURE
EXAMINER GROUP 2125

00862,022239

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Shigeyuki UZAWA et al.

Application No.: 09/864,309

Filed: May 25, 2001

For: EXPOSURE APPARATUS, COATING/ DEVELOPING SYSTEM, DEVICE MANUFACTURING SYSTEM, DEVICE MANUFACTURING METHOD, SEMICONDUCTOR MANUFACTURING FACTORY, AND EXPOSURE APPARATUS MAINTENANCE METHOD

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P.O. Box 1450
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REQUEST FOR RECONSIDERATION
AFTER FINAL ACTION

Sir:

In response to the Office Action dated February 26, 2004, Applicants request reconsideration of the above-identified application pursuant to 37 U.S.C. § 1.116, in view of the following remarks.:

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